## **PENDING CLAIMS**

The following is a list of currently pending claims. Please amend claims 1-4 and 8-11 as shown below.

(Currently amended) An array of thin film transistors comprising polysilicon, wherein the polysilicon is formed by a method comprising:
depositing a first layer of amorphous silicon;
depositing silicon nuclei on the first layer of amorphous silicon;
depositing a second layer of amorphous silicon over the first layer and the nuclei,
wherein conversion of the first layer to hemispherical grains before deposition
of the second layer is substantially prevented; and

annealing the first and second layers of amorphous silicon to induce

- 2. (Currently amended) The <u>array of thin film transistors</u> of claim 1, further comprising a charge storage region.
- 3. (Currently amended) The <u>array of thin film transistors</u> of claim 2, wherein the charge storage region is ONO-type.
- 4. (Currently amended) The <u>array of thin film transistors</u> of claim 2, wherein the charge storage region comprises a floating gate.
- 5. (Original) A monolithic three dimensional memory array comprising memory cells, said memory cells comprising polysilicon, any of said polysilicon crystallized by a method comprising:
  - embedding deposited silicon nuclei between layers of amorphous silicon; and crystallizing from the embedded silicon nuclei.
- 6. (Original) The monolithic three dimensional memory array of claim 5, wherein the memory cells comprise TFTs.

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crystallization.

- (Original) The monolithic three dimensional memory array of claim 5, where the memory cells comprise antifuses and either diodes or diode components.
- 8. (Currently amended) An array of thin film transistors comprising a channel regions, the channel regions formed by a method comprising: embedding deposited silicon nuclei between layers of amorphous silicon; and annealing the nuclei and amorphous silicon layers.
- 9. (Currently amended) The <u>array of thin film transistors</u> of claim 8, <u>each thin film</u> transistor of the array further comprising a charge storage region.
- 10. (Currently amended) The <u>array of thin film transistors</u> of claim 9, wherein the charge storage region is ONO-type.
- 11. (Currently amended) The <u>array of thin film transistors</u> of claim 9, wherein the charge storage region comprises a floating gate.

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## **CLAIM AMENDMENTS: DISCUSSION**

Claims 1-4 and 8-11 were amended to refer to an *array* of transistors rather than to an individual transistor. Support for these claim amendments is found, for example, at paragraphs [0052]-[0054] of the present application. These amendments do not constitute new matter.